

INFORMATION DISCLOSURE STATEMENT

Case Name. M. Megens 1-10-5
Serial No. 10/040017
Applicant: M. Megens, et al.
Filing Date: January 4, 2002
Group: 1756

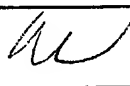
U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date

FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Subclass	Translation

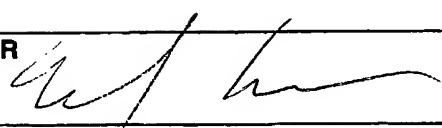
OTHER (including Author, Title, Date, Pertinent Pages, etc.)

	AA	Lee, K.Y., LaBianca, N., Rishton, S.A., Zolghamain, S., Gelorme, J.D., Shaw, J., Chang, T.H.-P., Micromachining Applications Of A High Resolution Ultrathick Photoresist, J. Vac. Sci. Technol. B 13(6) Nov/Dec 1995, pp. 3012-3016.

***References listed beyond AZ would list as AA-1, AB-2, AC-3 thru AZ-26.

***Note First Page ONLY Header/Footer. Subsequent pages must ONLY have page # layout as header

EXAMINER



DATE CONSIDERED

6/29/04

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant